

O I P E Docket No.: 060188-0658

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In the Application of : Customer Number: 20277  
Masashi HAMANAKA, et al. : Confirmation Number: 8488  
Application No.: 10/671,502 : Group Art Unit: 3723  
Filed: September 29, 2003 : Examiner: RACHUBA, MAURINA T  
:  
For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR  
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

**AMENDMENT**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated January 27, 2006, having a three-month shortened statutory period for response set to expire April 27, 2006, a one-month extension up to and including May 27, 2006 being filed concurrently herewith, please amend the above-identified application as follows.